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CONFIRMATION NO. 8391

SERIAL NUMBER 09/928,860	FILING DATE 08/13/2001  RULE	CLASS 427	GROUP ART UNIT 1762	ATTORNEY DOCKET NO. ATMI-0357-DIV
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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a CON of 09/251,890 02/19/1999 PAT 6,316,797 \*

(\*)Data provided by applicant is not consistent with PTO records.

*EBC*

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

none *EBC*

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 09/14/2001

Foreign Priority claimed	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY	SHEETS DRAWING	TOTAL CLAIMS	INDEPENDENT CLAIMS
35 USC 119 (a-d) conditions met	<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after	CT	7	28	27
Verified and Acknowledged	<i>EBC</i>	Initials			5

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## TITLE

Scalable lead zirconium titanate (PZT) thin film material and deposition method, and ferroelectric memory device structures comprising such thin film material

 All Fees

FILING FEE  
RECEIVED  
1216

FEES: Authority has been given in Paper  
No. \_\_\_\_\_ to charge/credit DEPOSIT ACCOUNT  
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- 1.16 Fees ( Filing )
- 1.17 Fees ( Processing Ext. of time )
- 1.18 Fees ( Issue )
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